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42 U.S.C. § 171  
U.S. PATENT & TRADEMARK OFFICE  
Initial Review  
RESPONSE UNDER 37 CFR 1.116 - EXPEDITED  
PROCEDURE - EXAMINING GROUP 1112

GROUP 1100

#9/B  
(N.E.)

# 14/D

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of:

Takeshi FUKUNAGA et al.

) Examiner M. Padgett

Serial No. 08/519,420

) Art Unit 1112

Filed: August 25, 1995

)

For: A METHOD OF MANUFACTUR-

)

ING A SEMICONDUCTOR DEVICE

)

INCLUDING LASER IRRADIATION

)

FOLLOWED BY THERMAL .

)

ANNEALING

) Docket No. 0756-1398

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, BOX AF, Washington, D.C. 20231, on December 3, 1996.

*Deborah T. Tomme*

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AMENDMENT AFTER FINAL REJECTION

Honorable Assistant Commissioner for Patents  
BOX AF  
Washington, D.C. 20231

Sir:

In response to the final rejection Office Action mailed September 3, 1996, please amend the above identified application as follows.